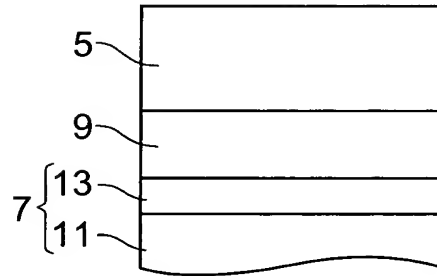
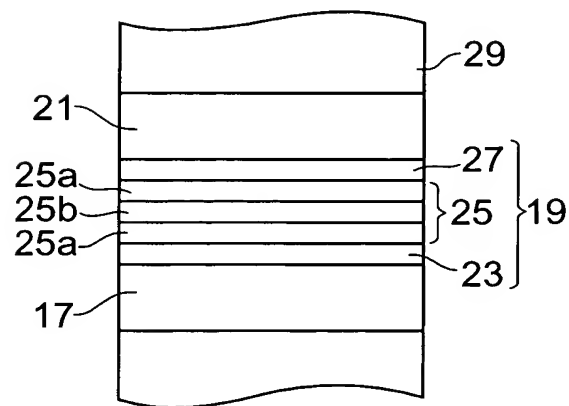
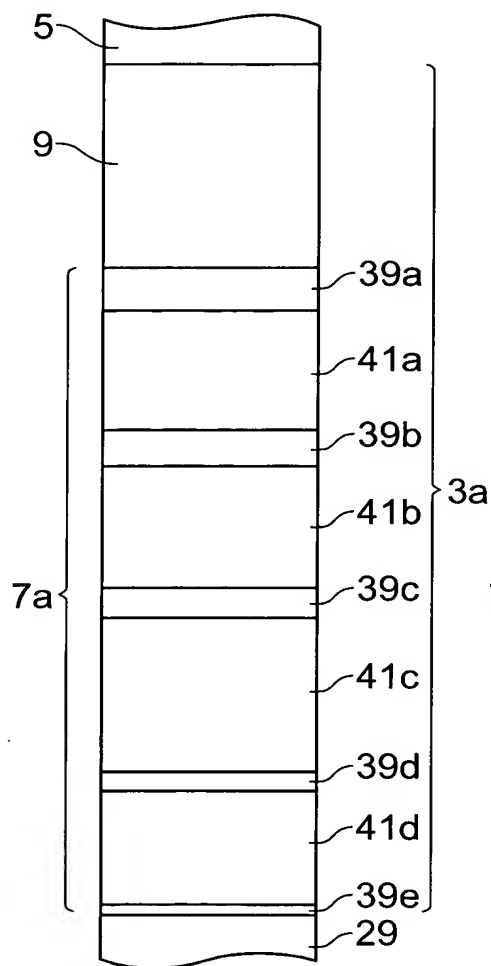
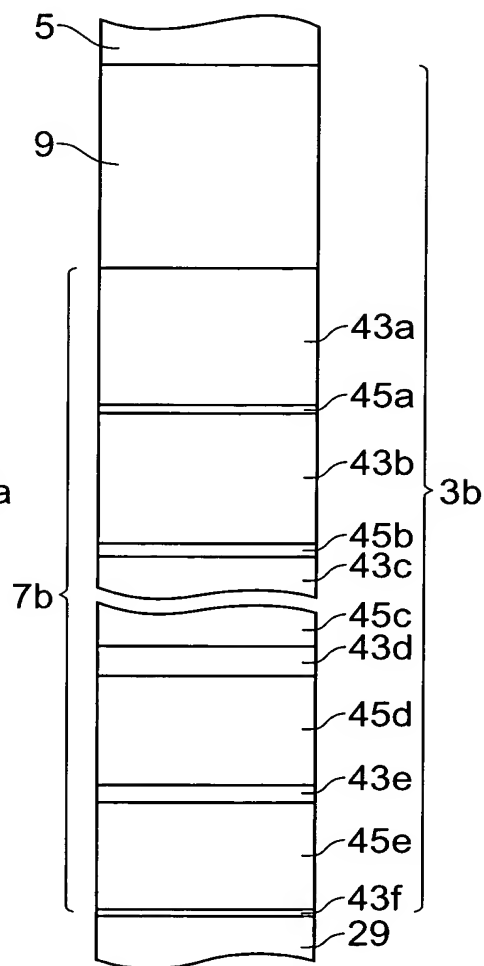


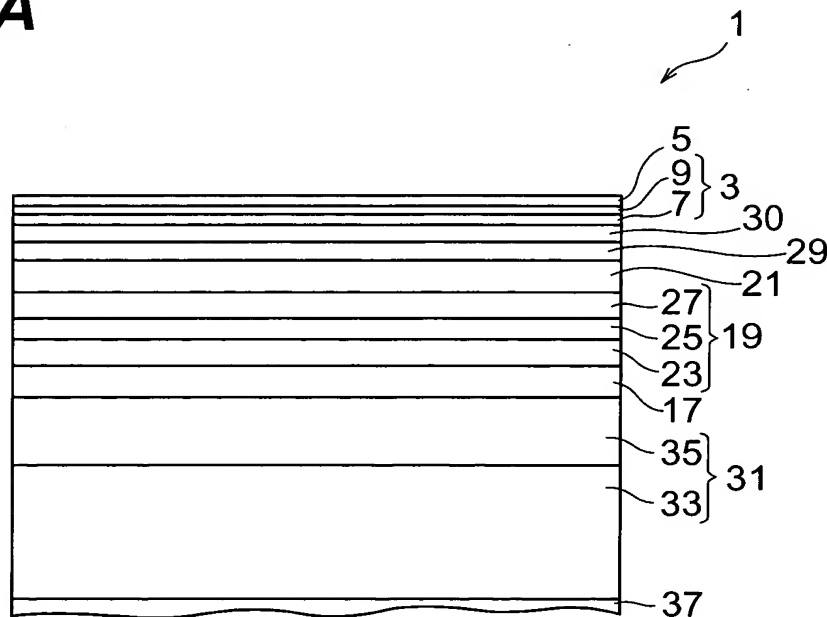
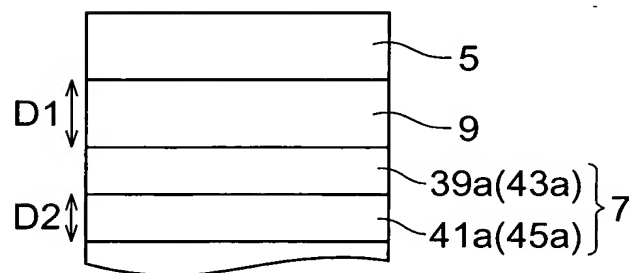
2/13

Fig.2A**Fig.2B**

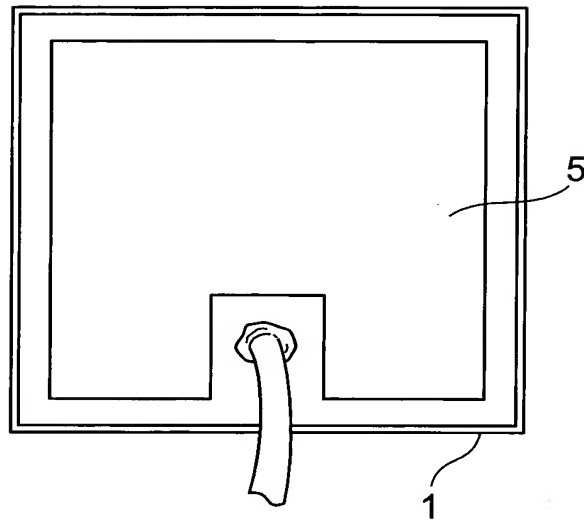
3/13

Fig.3A**Fig.3B**

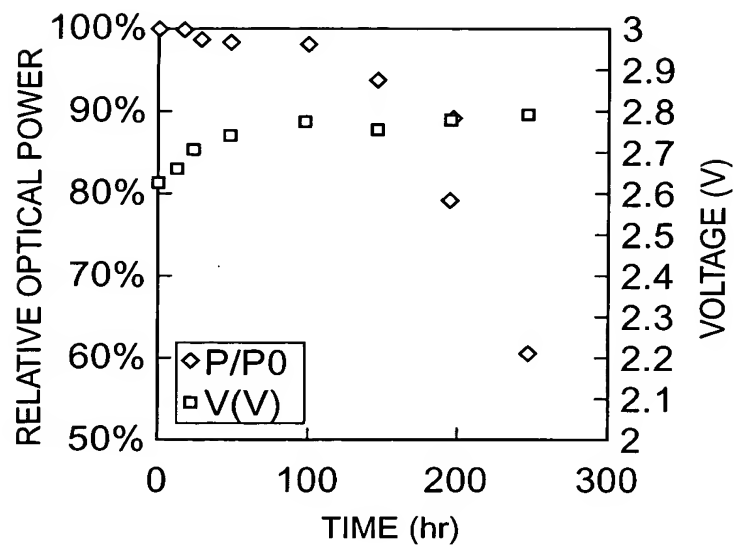
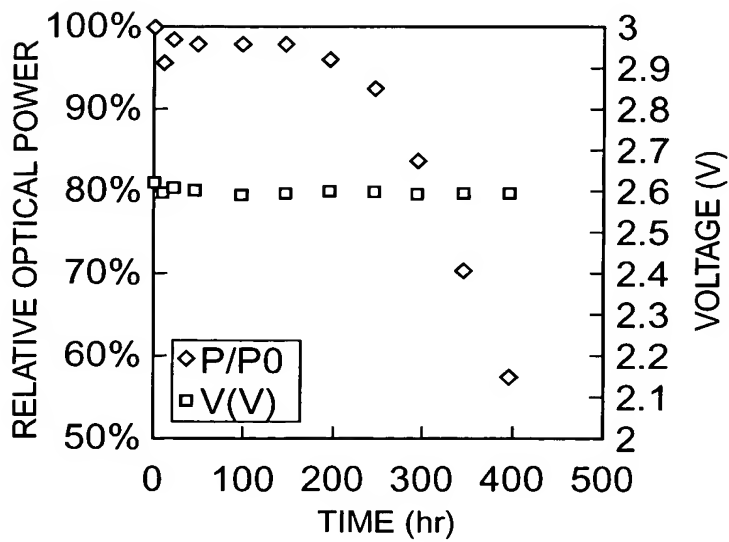
4/13

Fig.4A**Fig.4B**

5/13

Fig.5

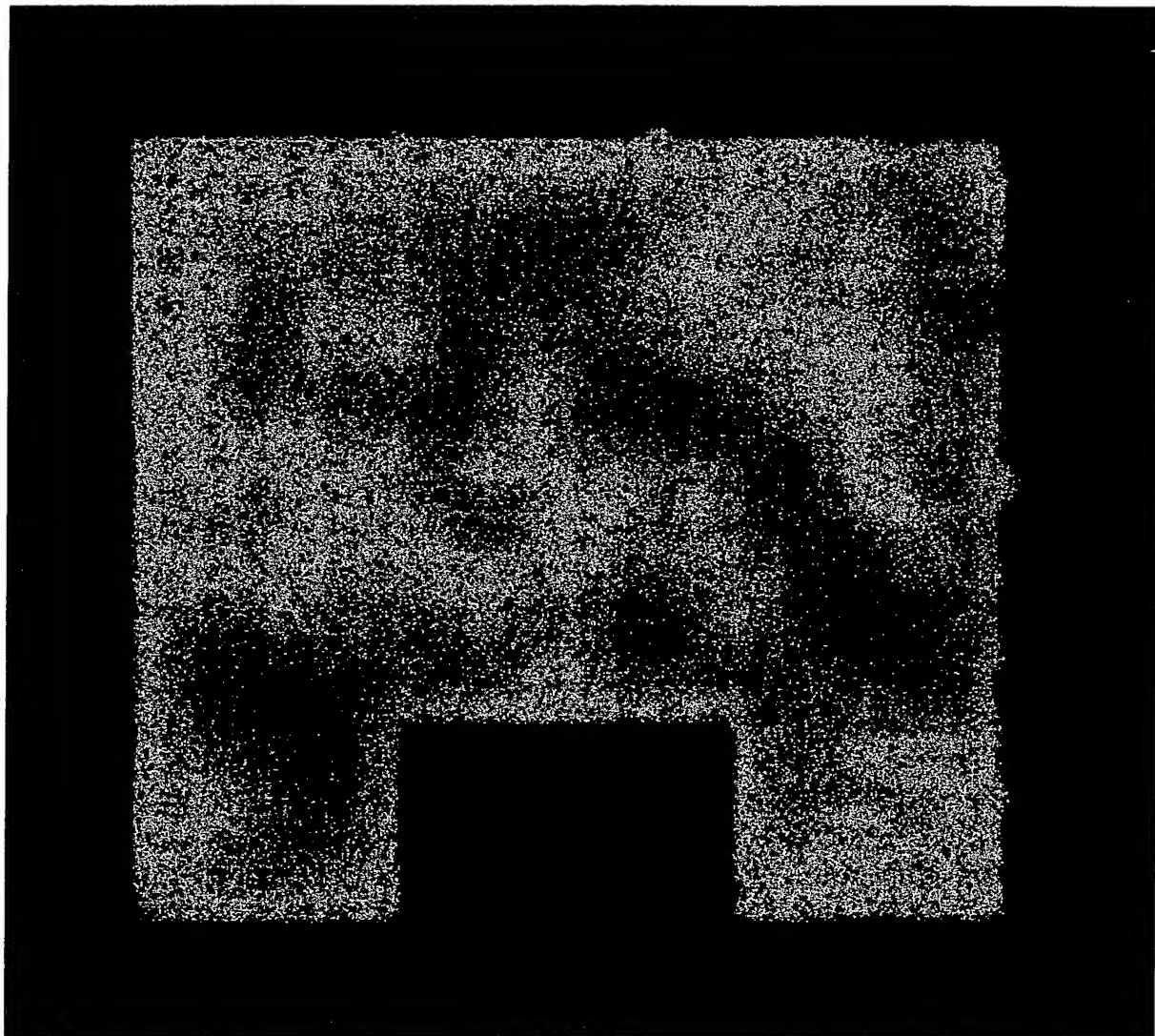
6/13

Fig.6A**Fig.6B**

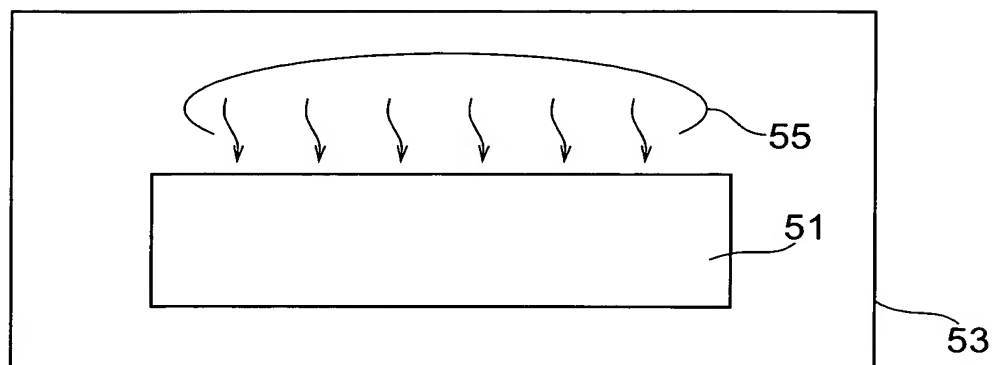
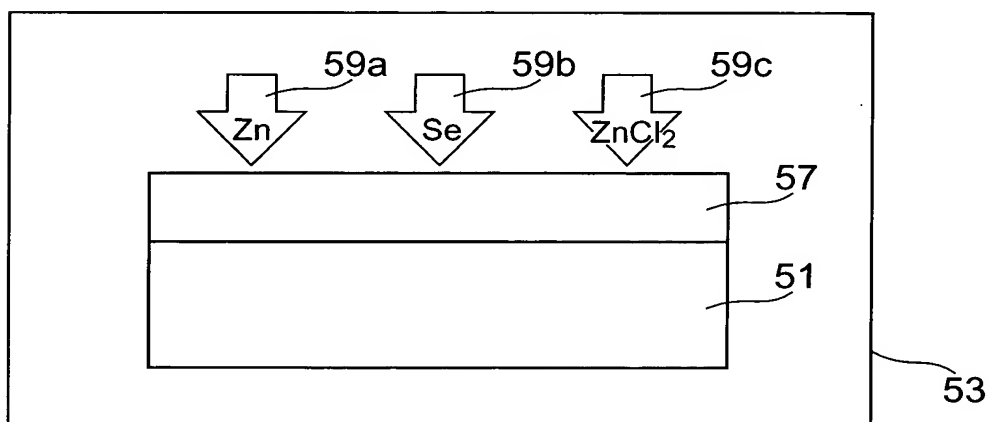
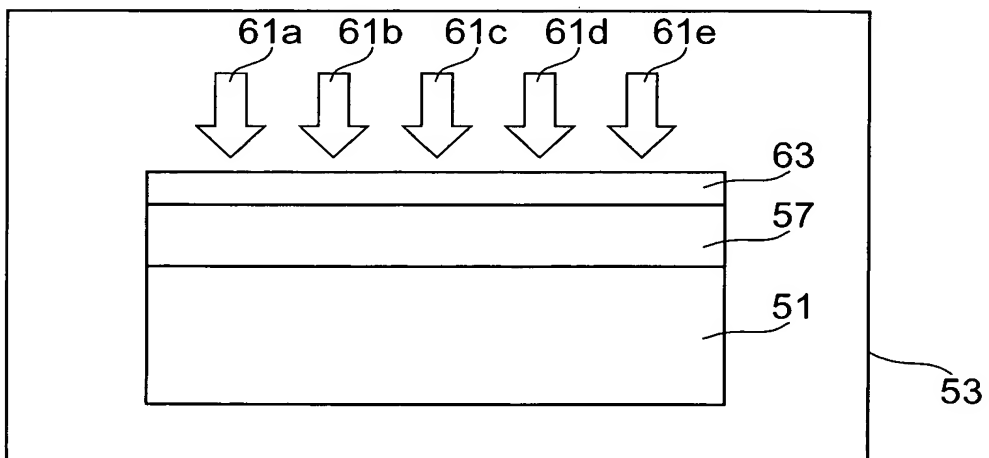
Applicant(s): Takao Nakamura et al.
SEMICONDUCTOR OPTICAL DEVICE, METHOD OF
FORMING CONTACT IN SEMICONDUCTOR OPTICAL
DEVICE

7/13

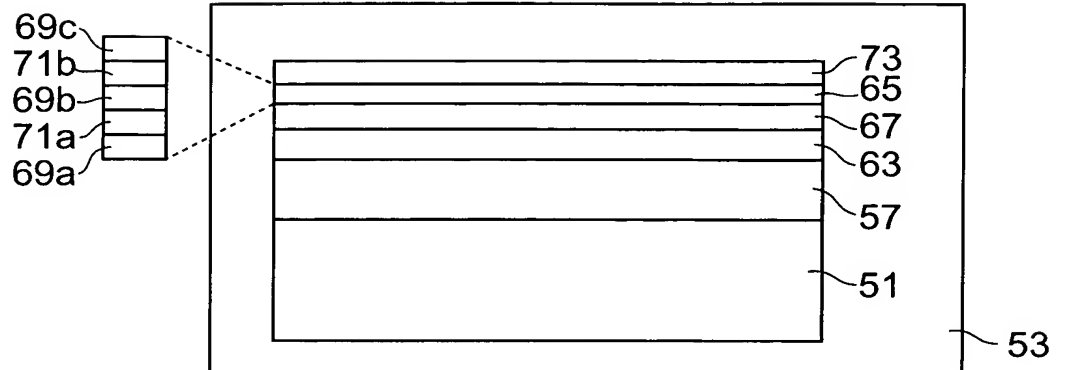
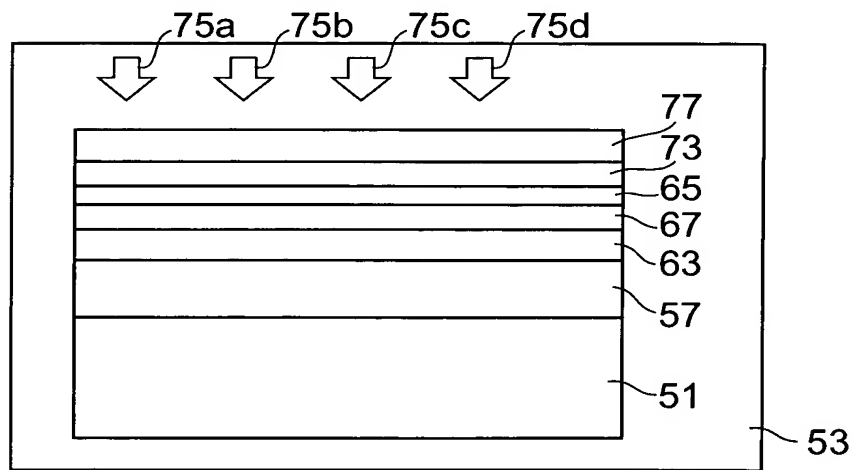
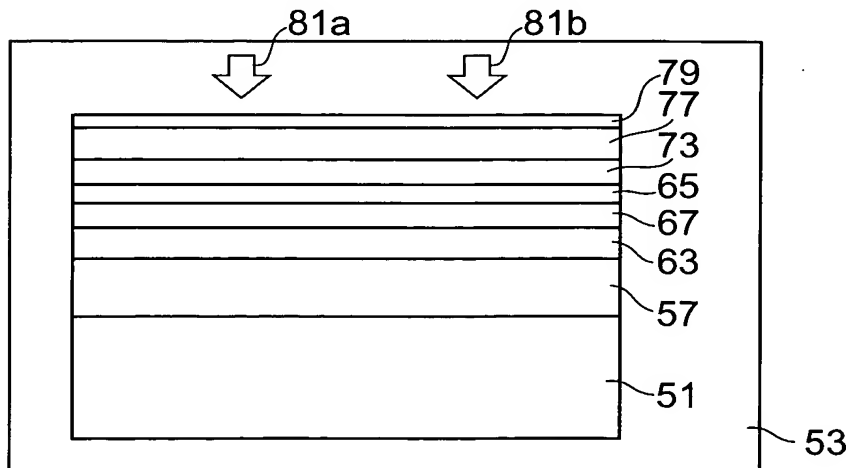
Fig.7



8/13

Fig.8A**Fig.8B****Fig.8C**

9/13

Fig.9A**Fig.9B****Fig.9C**

10/13

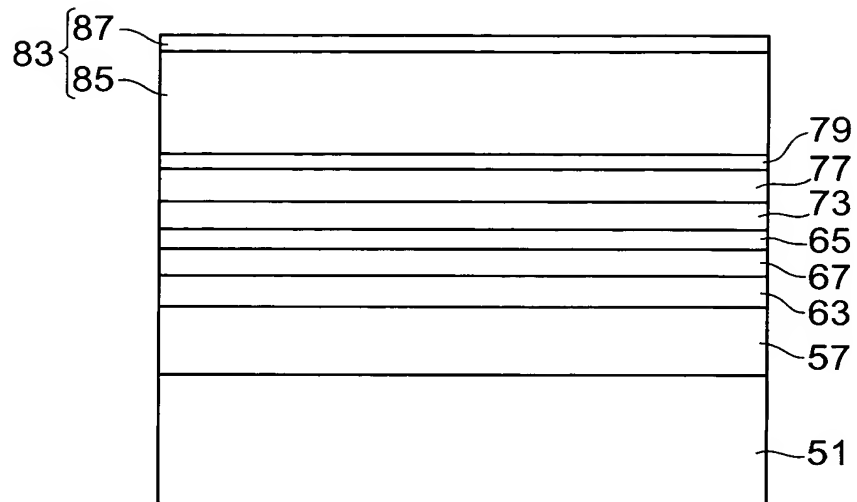
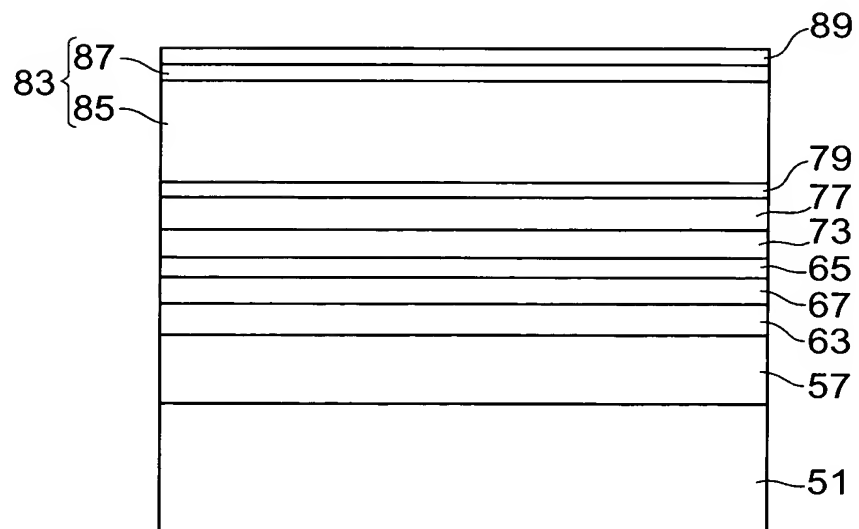
Fig.10A**Fig.10B**

Fig.11B

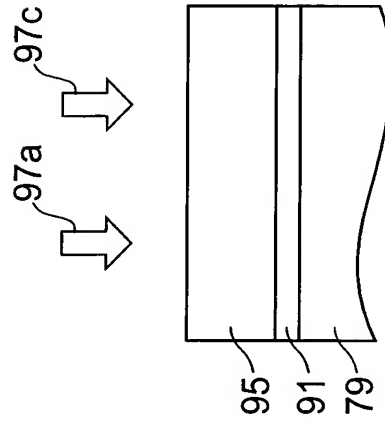
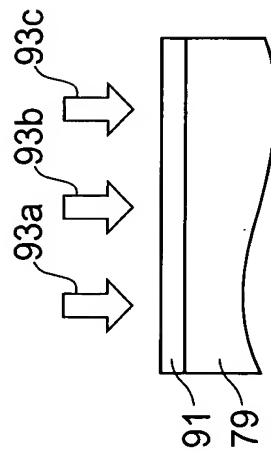


Fig.11A



12/13

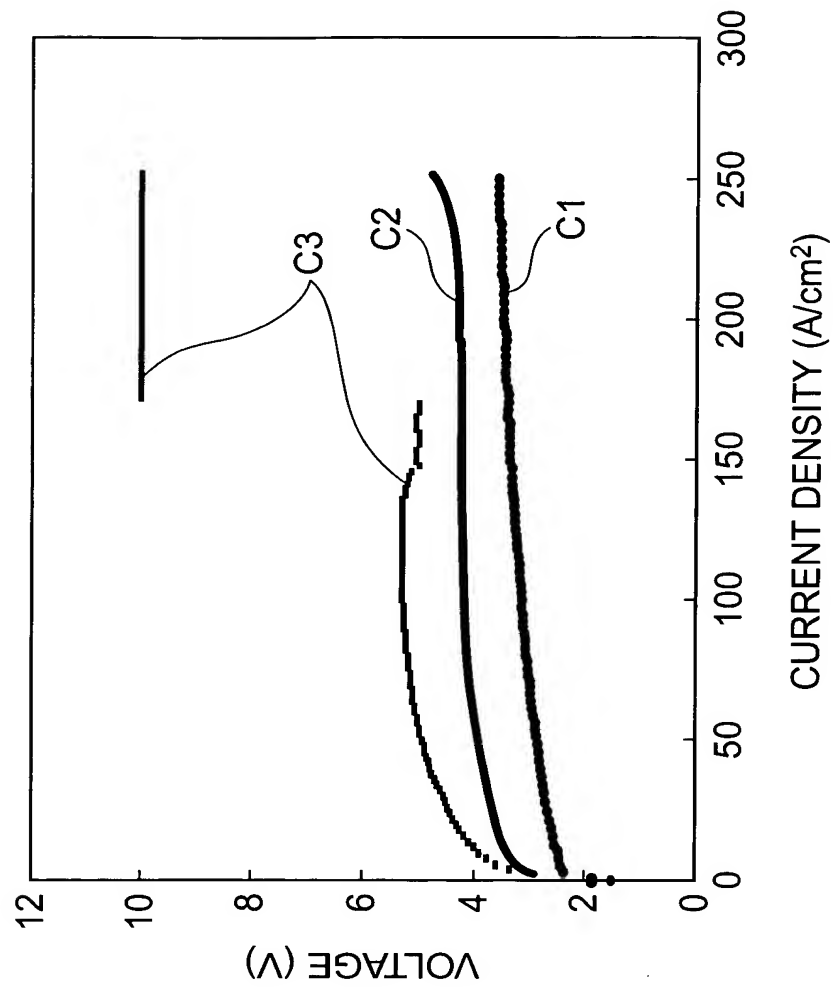
**Fig.12**

Fig.13

